



NOTES

1. REFLECTION CUTOFF, TRANSMISSION START WAVELENGTH: 650 nm
2. CLEAR APERTURE: >90%CA
3. SURFACE QUALITY(S1, S2): 40/20(S/D)
4. WAVEFRONT ERROR(RMS): $\lambda/4@633$ nm
5. PARALLELISM(S1, S2): <3 arcmin
6. COATING:
 FILTER COATING(S1): $T_{avg}>90\%$, $T_{abs}>85\%@400-635$ nm, 45° AOI
 $R_{avg}>95\%$, $R_{abs}>90%@685-1200$ nm, 45° AOI
 AR COATING(S2): $R_{abs}<2%@400-635$ nm, 45° AOI
7. CHAMFER: <0.35 mm, 45°

DRAWING PROJECTION			LBTEK			
	NAME	DATE				
DRAWN	LZHOU	JUL./30th/24	SHORTWAVE DICHOIC MIRROR Ø25.4 mm x 3.2 mm, 650 nm			
APPROVAL	WCHENG	JUL./30th/24	MATERIAL	WEIGHT	SCALE	REV
FOR INFORMATION ONLY NOT FOR MANUFACTURING PURPOSES			UVFS	3.6 g	2:1	A